





RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE
GROUP 2823
PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q64059

Shigeo ISHIKAWA

Appln. No.: 09/832,093

Group Art Unit: 2823

Confirmation No.: 8684

Examiner: Khiem D. Nguyen

Filed: April 11, 2001

FILM FORMING METHOD IN WHICH FLOW RATE IS SWITCHED

RESPONSE UNDER 37 C.F.R. § 1.116

**MAIL STOP AF** 

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:  $f_{C_i}$ 

For:

In response to the Office Action dated August 1, 2003, please consider the following

remarks.

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REMARKS .....

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